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35. (Original) The apparatus according to Claim 20, wherein the other chamber is at least one of a semiconductor workpiece holding chamber or a semiconductor workpiece processing chamber, the semiconductor workpiece processing chamber being at least one of lithography module, a metal deposition module, an etching module, or a heating or cooling module.

36. (Original) The apparatus according to Claim 20, wherein the other chamber is a stocker for stocking semiconductor workpiece transport containers therein.

37. (Original) The apparatus according to Claim 20, wherein the other chamber is a load lock chamber.

38. (Original) The apparatus according to Claim 20, wherein the other chamber is a front end module providing an interface between the semiconductor workpiece transport containers and the first chamber.

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40. (Previously Presented) A substrate processing apparatus comprising:

a transport chamber capable of having a controlled atmosphere therein;

at least one substrate holding module for holding a substrate, the at least one holding module being communicably connected to the transport chamber for allowing transfer of the substrate between the at least one holding module and transport chamber;

a first transport vehicle movably mounted in the transport chamber, the first vehicle having a first movable substrate transfer arm adapted for moving the substrate between the

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transport chamber and the at least one substrate holding module; and

a second transport vehicle movably mounted in the transport chamber, the second vehicle having a second movable substrate transfer arm adapted for moving the substrate between the transport chamber and the at least one substrate holding module;

wherein the transport chamber has a section defining a tube and has several linear travel paths between opposing walls of the tube for the first and second vehicles to travel in the transport chamber, and wherein the first vehicle extends across the tube from proximate one of the opposing walls to proximate another of the opposing walls and the first and second vehicles are capable of moving past one another between the opposing walls of the tube when the first vehicle is using one of the travel paths and the second vehicle is using another of the travel paths.

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41. (Original) The apparatus according to Claim 40, wherein the travel paths are generally aligned with each other.

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42. (Original) The apparatus according to Claim 40, wherein the travel paths extend longitudinally in the transport chamber.

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43-71. (Cancelled)